In the Abstract

Please substitute the following amended Abstract for the Abstract as currently pending (deleted matter is shown by strikethrough and added matter is shown by underlining):

The invention relates to a method for determining an actual value of at least one system parameter or a deviation from a set value of at least one parameter of a system (1; 25; 35; 46) for the treatment of an eye [[(40)]] using a treatment laser beam [[(3)]] emitted by said system (1; 25; 37; 46). According to the invention, the surface of a calibrating body [[(11)]] is ablated with at least a partial beam of the treatment laser beam [[(3)]] with a predetermined ablation program. The surface ablated by the treatment laser beam [[(3)]] is examined by means of aberrometry and/or profilometry. The actual value of the system parameter or the deviation from the set value of the system parameter is determined on the basis of the examination data detected during the examination.